

FIG. 2

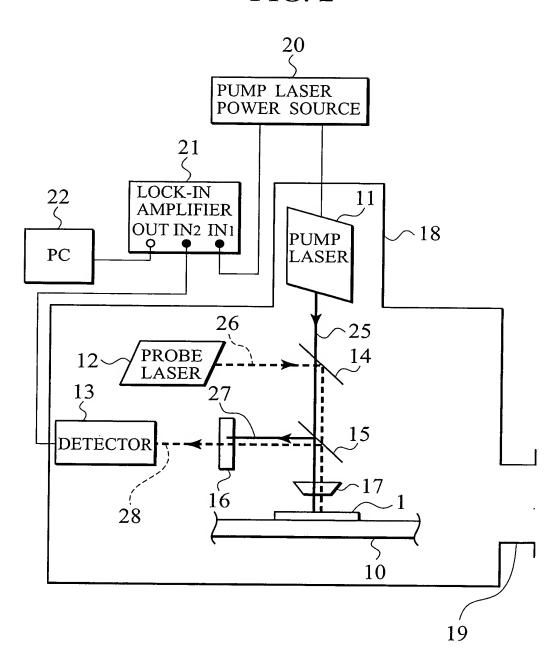


FIG. 3

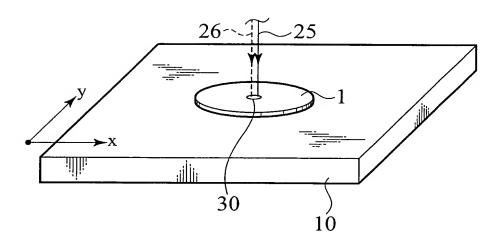


FIG. 4

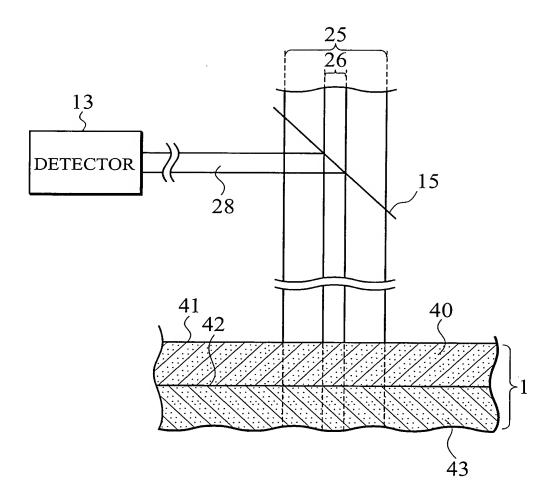
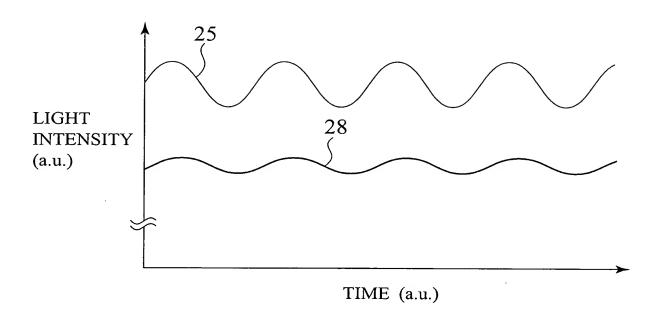
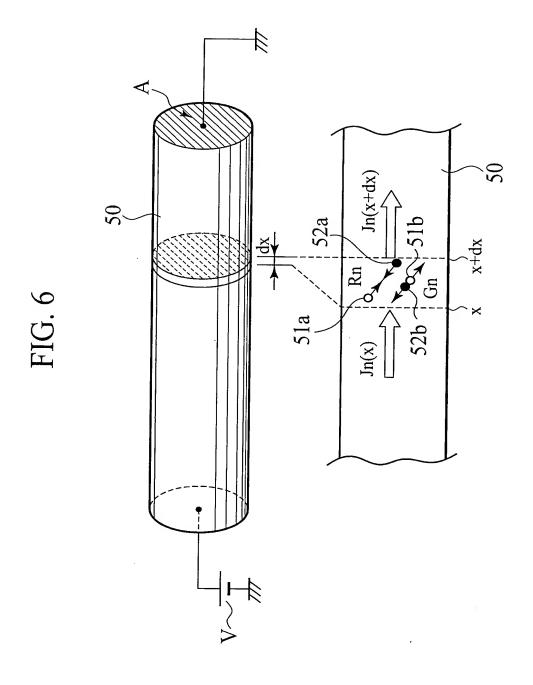


FIG. 5





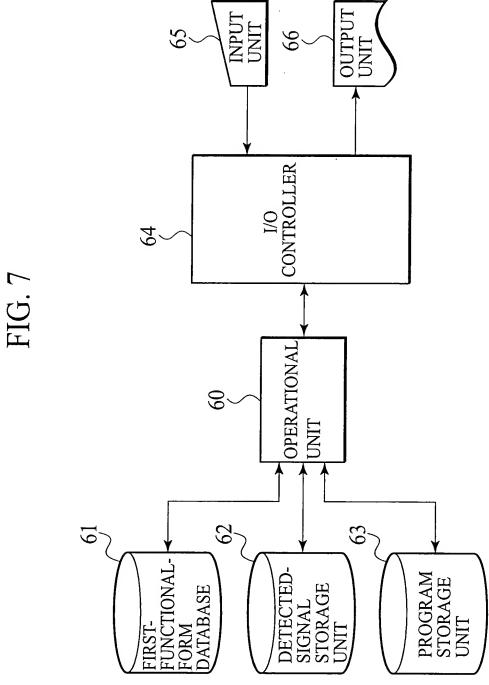
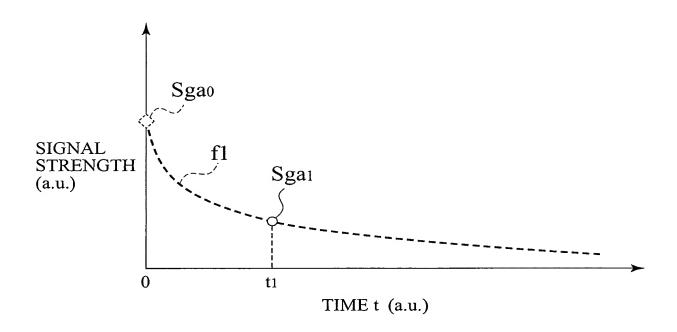


FIG. 8



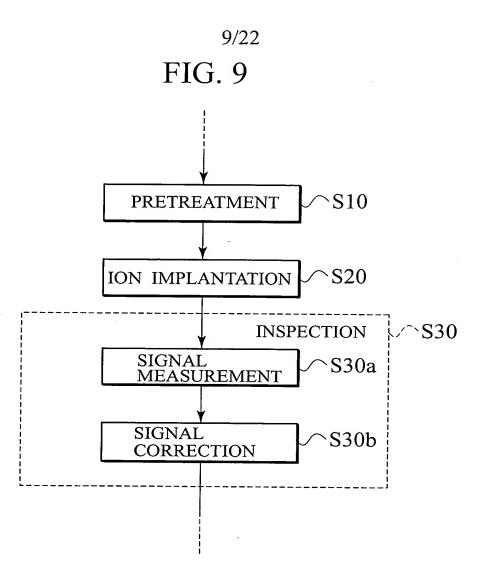
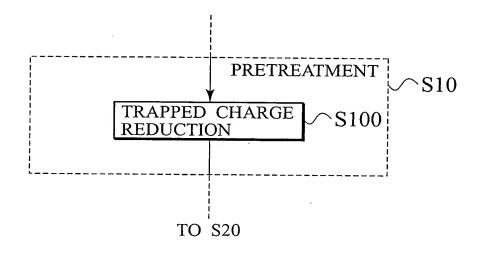
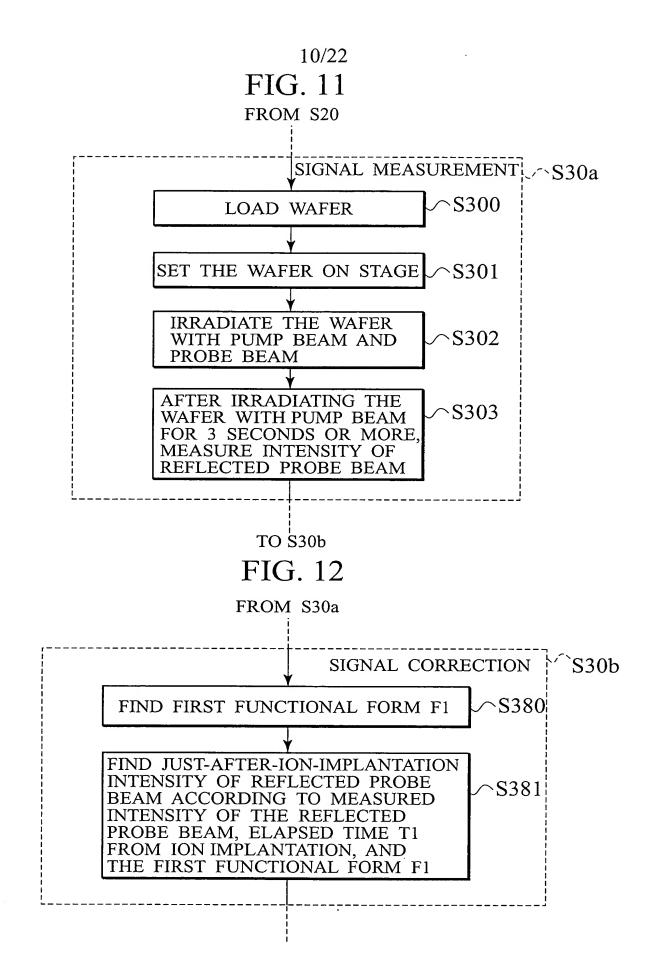
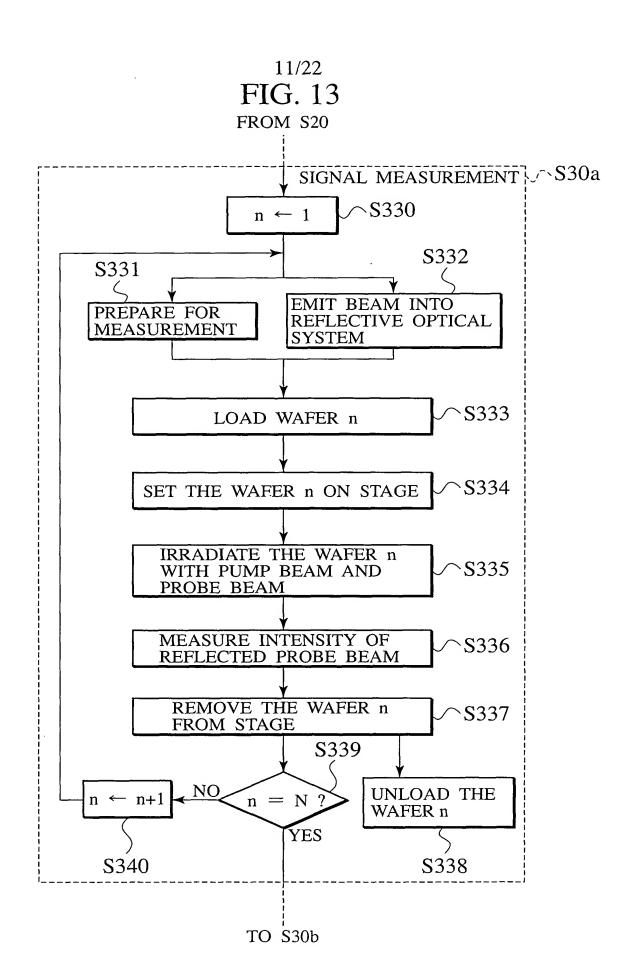


FIG. 10







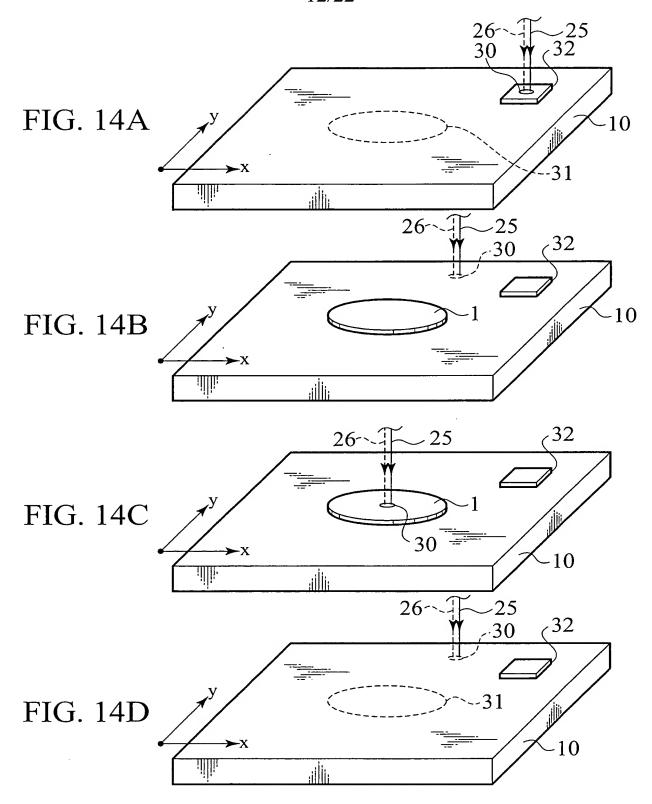
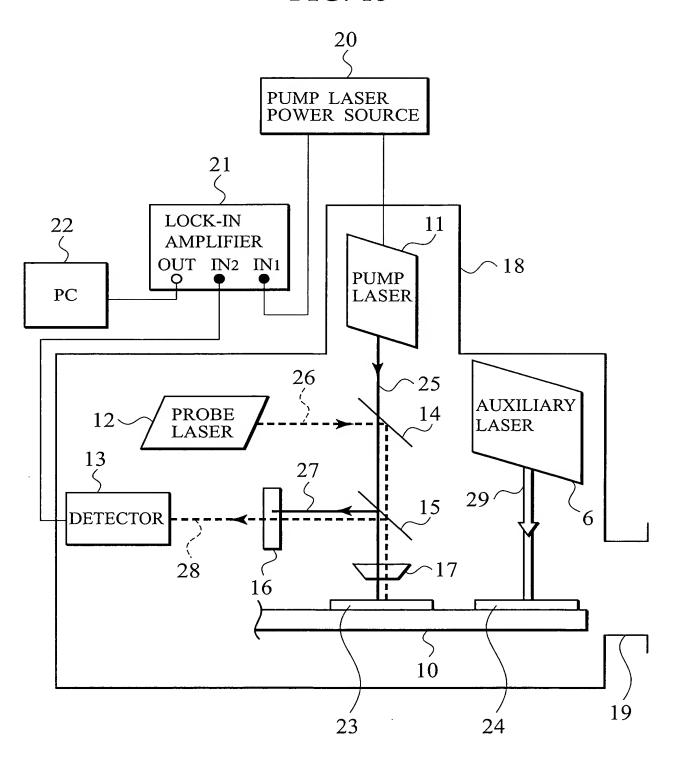


FIG. 15



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FIG. 16

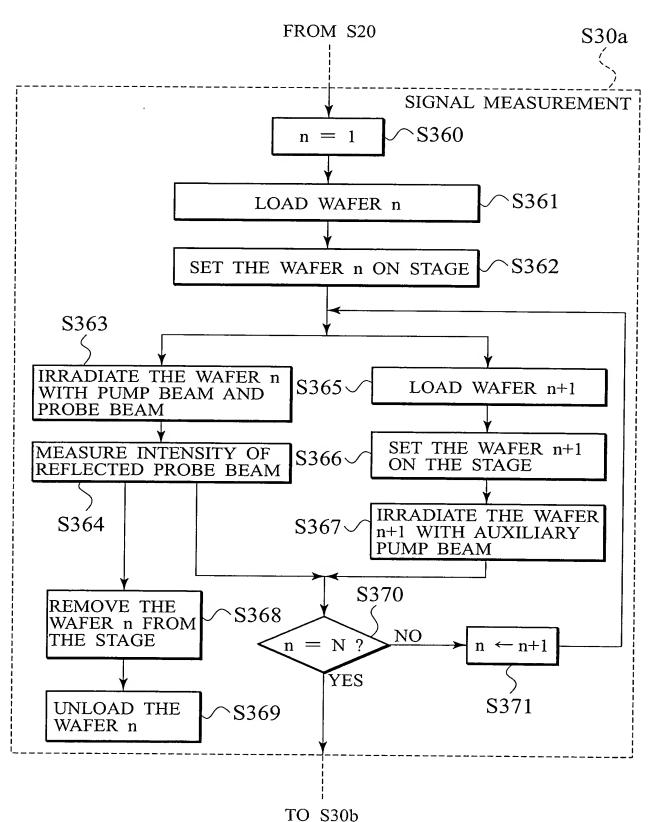


FIG. 17

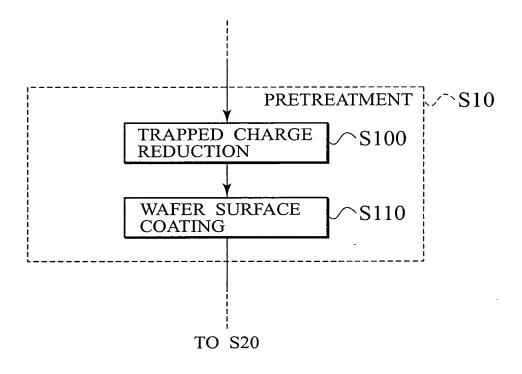


FIG. 18

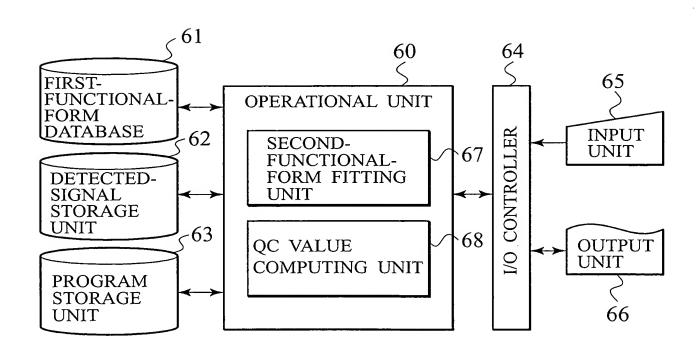


FIG. 19

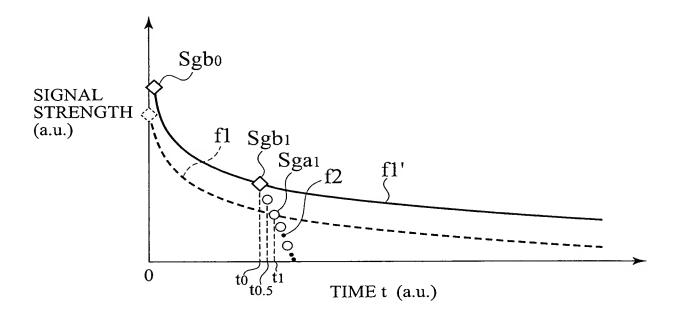
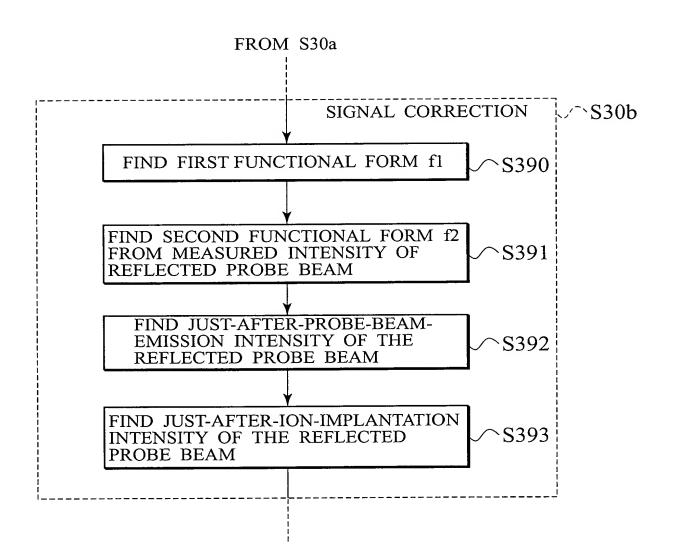


FIG. 20



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INTO DOSE (%)	STANDARD DEVIATION (DOSE) %	0.65	0.38	0.51	2.42
	ION IMPLANTER	כ	ر ر	ວ	ر ر
	DOSE ANGLE	+5°	5E+13 PARALLEL	-2°	-5°
	DOSE	5E+13	5E+13	5E+13	5E+13
	ACCELERATION ENERGY	500keV	500keV	500keV	500keV
	IONIC	Ъ	Ъ	Ъ	Ъ
	OXIDE FILM THICKNESS	8nm	8nm	8nm	8nm

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FIG. 22

i	IN-PLANE
	UNIFORMITY
	OF SIGNAL
	STRENGTH
	CONVERTED
	INTO DOSE (%)
	STANDARD
5	DEVIATION
`	(DOSE) %
7	

IONIC SPECIES	ACCELERATION ENERGY	DOSE	ANGLE	ION IMPLANTER	STANDARD DEVIATION (DOSE) %
В	3keV	3E+15	'+2°	A	0.483694052
В	3keV	3E+15	PARALLEL	A	0.602034279
В	3keV	3E+15	'-2°	A	0.633528518

FIG. 23

TILT ANGLE	TWIST ANGLE	IN-PLANE UNIFORMITY IN DOSE (%)	
0	0	1.01	
0	0	1.35	
7	0	1.24	
5	180	1.36	ION BEAM AND WHEEL
7	180	1.77	ROTATION AXIS ARE PARALLEL
9	180	2.71	
7	203	1.40	
5	210	0.874	
5	225	1.16	
5	240	0.913	
7	247	2.75	
5	255	0.54	IMPLANTING
5	270	0.60	CONDITIONS TO REDUCE
7	270	1.43	CIRCUMFERENTIAL ANGULAR VARIATIONS

FIG. 24

\sim					
CONVERTED INTO DOSF (%)	STANDARD DEVIATION (DOSE) %	1.39	1.34	1.10	0.92
	ION IMPLANTER	B	В	В	В
	DOSE ANGLE	2°	1E+15 PARALLEL	-2°	-5°
	DOSE	1E+15	1E+15	1E+15	1E+15
	ACCELERATION ENERGY	30	30	30	30
	IONIC SPECIES	В	В	В	В
	OXIDE FILM THICKNESS	8pm	8nm	mu'8	8nm

FIG. 25

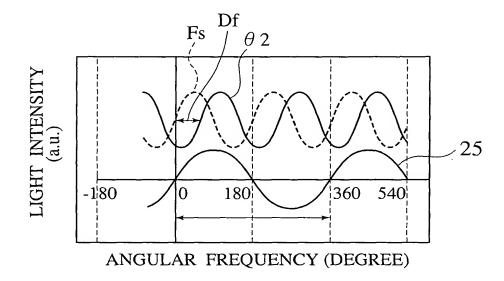


FIG. 26A

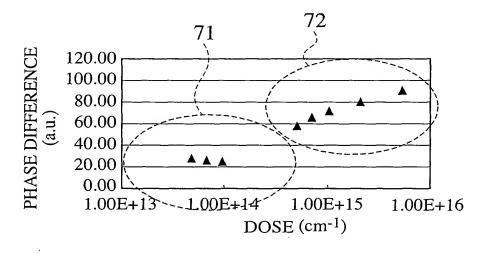


FIG. 26B

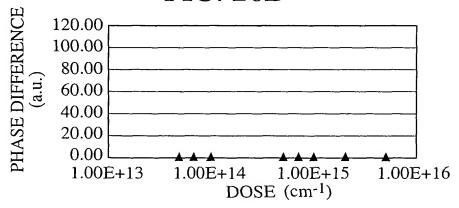


FIG. 27

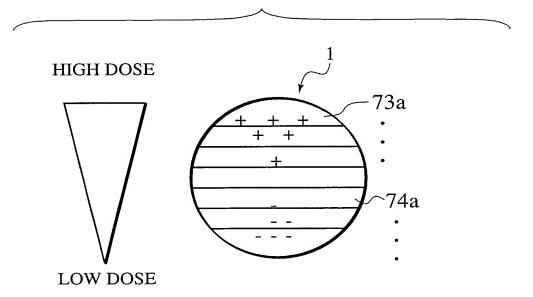


FIG. 28

